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CONFIRMATION NO. 4998

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|--|---|----------------------------------|---|--|--------------------------------|
| SERIAL NUMBER 10/518,025 | FILING OR 371(c) DATE 12/15/2004 RULE | CLASS 438 | GROUP ART UNIT 2812 | ATTORNEY DOCKET NO. 263261US0PCT | |
| APPLICANTS Hitoshi Kato, Tokyo, JAPAN; Koichi Orito, Tokyo, JAPAN; Hiroyuki Kikuchi, Tokyo, JAPAN; Shingo Maku, Tokyo, JAPAN; | | | | | |
| ** CONTINUING DATA ***** This application is a 371 of PCT/JP04/00370 01/19/2004 <i>MDA 9/9/05</i> | | | | | |
| ** FOREIGN APPLICATIONS ***** JAPAN 2003-016659 06/24/2003 <i>MDA 9/9/05</i> | | | | | |
| Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Verified and Acknowledged <i>Monica D. Pinner MDA</i> Examiner's Signature Initials | | STATE OR COUNTRY JAPAN | SHEETS DRAWING 4 | TOTAL CLAIMS 15 | INDEPENDENT CLAIMS 2 |
| ADDRESS 22850 | | | | | |
| TITLE Method of cvd for forming silicon nitride film on substrate | | | | | |
| FILING FEE RECEIVED 900 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit | | |